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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Comple	ete if Known		
Application Number 10/570,054			
Filing Date	February 28, 2006		
First Named Inventor	Mi Wang		
Art Unit	2863		
Examiner Name	Teixeira Moffat,		
Attorney Docket Number	7095UL-1 Jonathan	C.	

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite No.1	Document Number Number-kind Code ^{2 (d known)}	Publication Date MM-DD-YYYY	Name of Patentee of Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
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Examiner Initials*	Cite No.1	Foreign Patent Document Country Code ³ ; Number ⁴ ; Kind Code ⁵ (if known)		Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T6	
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OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)					
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		G. P. Lucas et al., "Measurement of the solids volume fraction and velocity distributions in solids-liquid flows using dual-plane electrical resistance tomography", Flow Measurement and Instrumentation, vol. 10, 1999, pp. 249-258; XP008040707, p. 250, left-hand column, last paragraph - p. 252, left-hand column.			
		B. S. Hoyle et al., "Design and application of a multi-modal process tomography system" Measurement Science and Technology, vol. 12, 2001, pp. 1157-1165; XP008040617 abstract.			
		M. Wang et al. "Characterization of gas-water flow using electrical resistance imaging" 11 th International Conference on Multiphase 03, June 13, 2003, pp. 595-604; XP008040620, Italy, p. 598.			
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Examiner Signature	/Jonathan Teixeira Moffat/	Date Considered	09/21/2010

^{*}EXAMINER: Initial if reference is considered, whether or not citation is in conformance and not considered. Include copy of this form with next communication to applicant.